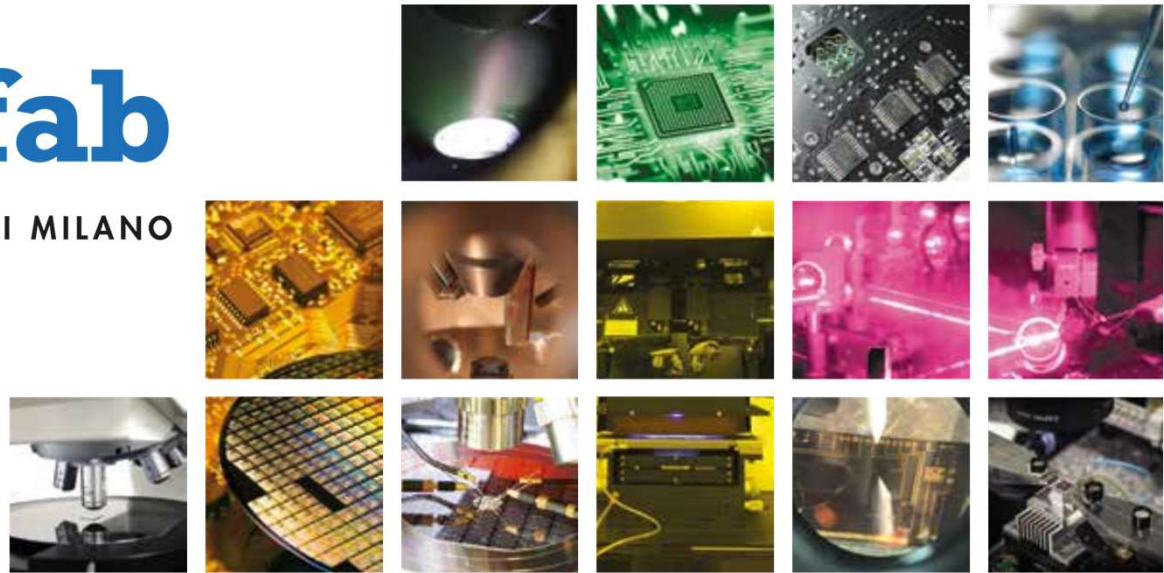


polifab
POLITECNICO DI MILANO



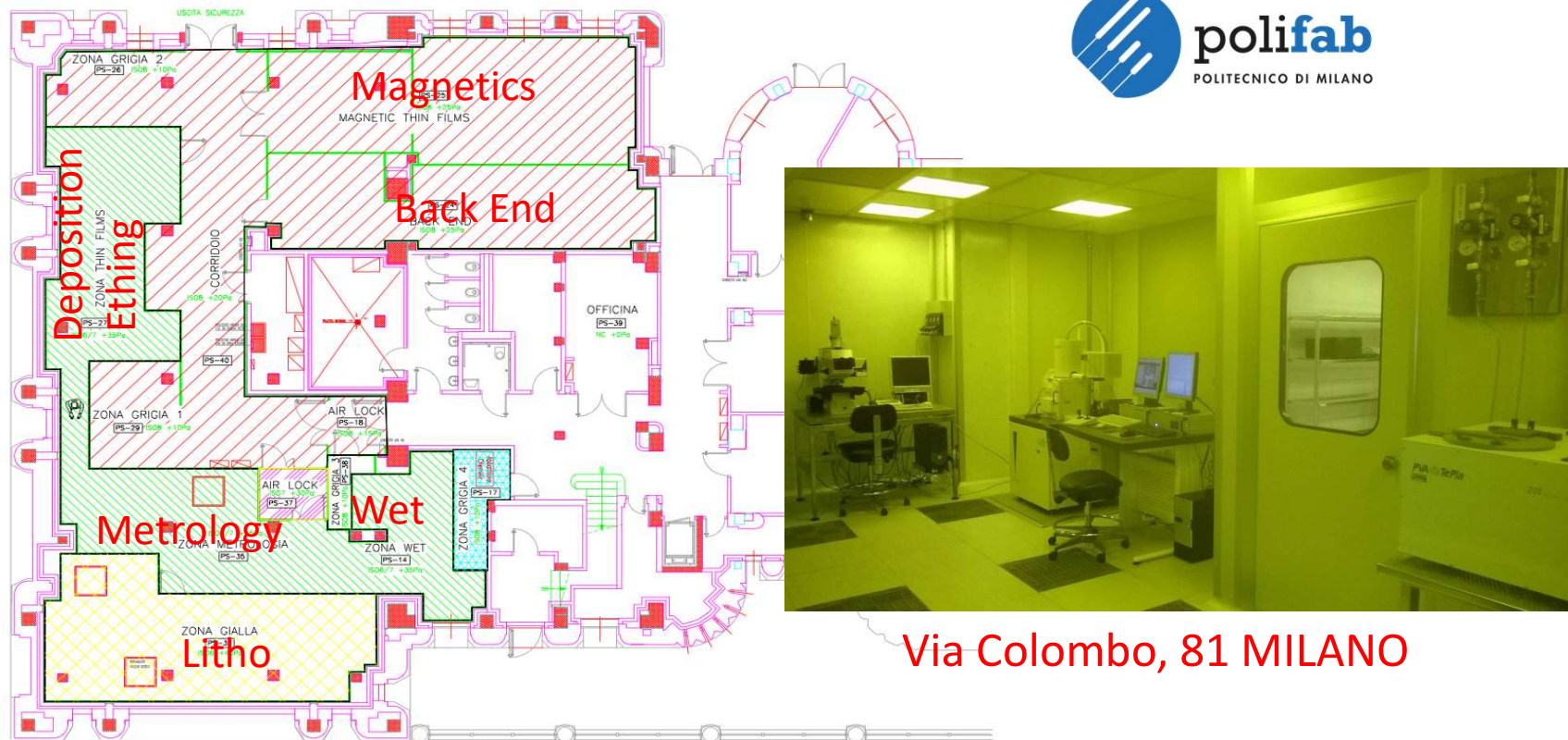
Polifab – a Micro-nano fabrication facility @ PoliMI

A. L. Lacaita

Facts

400 m² clean-room with 6" industrial grade equipment

Mission: enabling innovative concepts in nanoelectronics, photonics, MEMs, microfluidics, biosensors

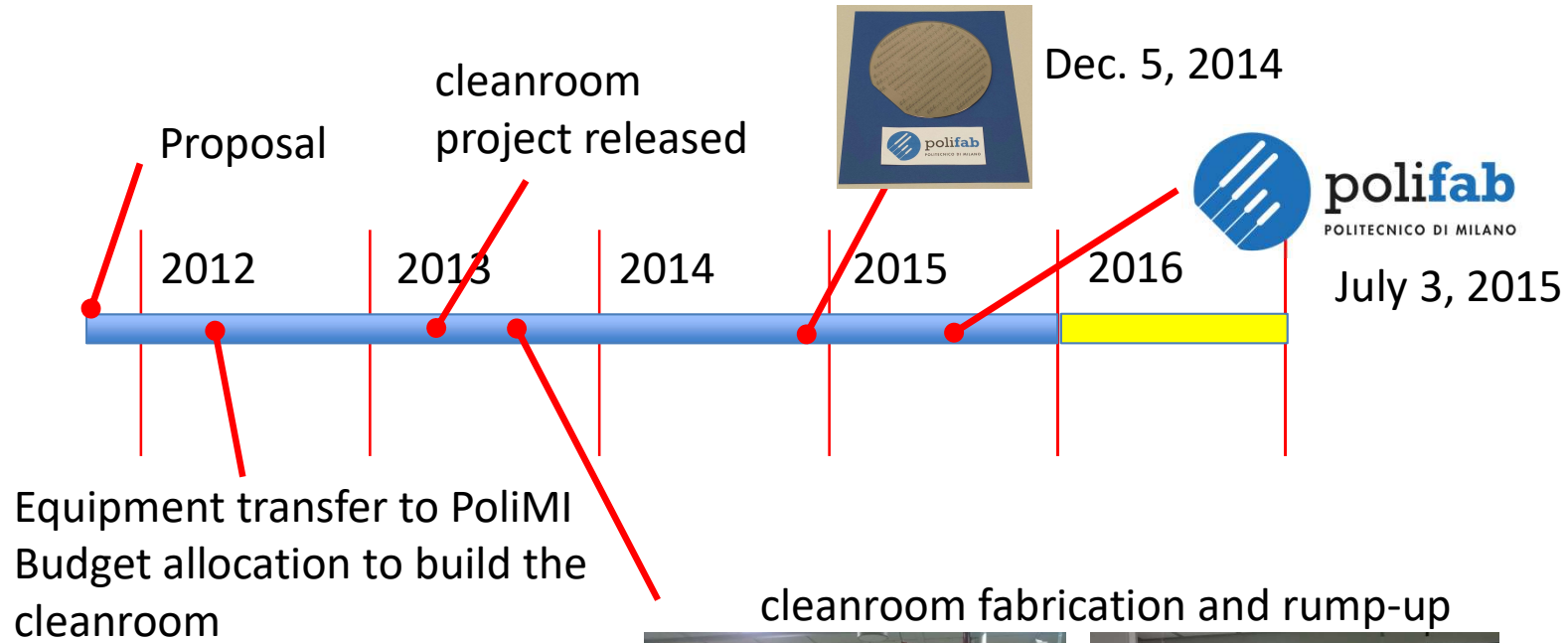


Via Colombo, 81 MILANO

Outline

- From the first proposal to cleanroom opening
- Cleanroom structure and equipment
- Research projects
- Governance and access options

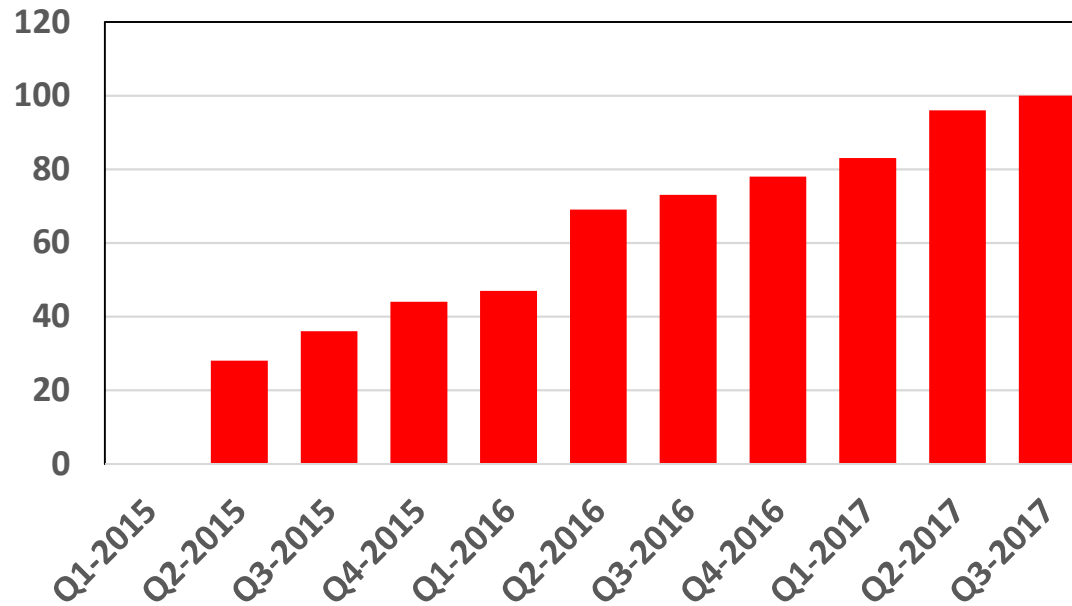
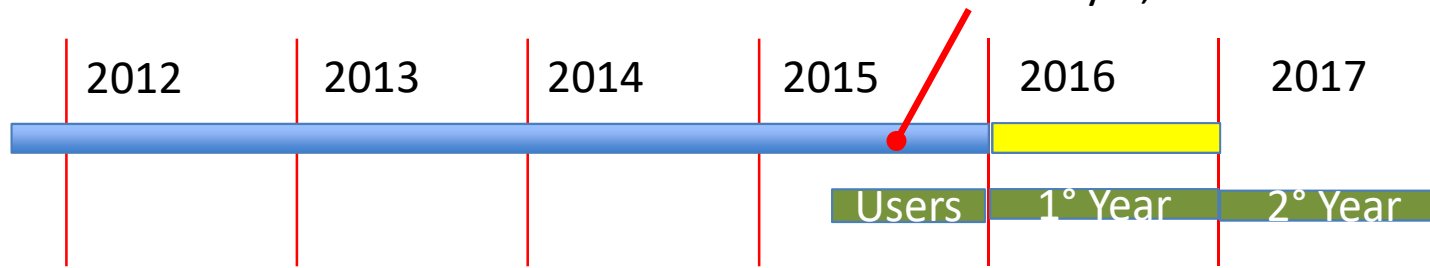
Timeline 2016



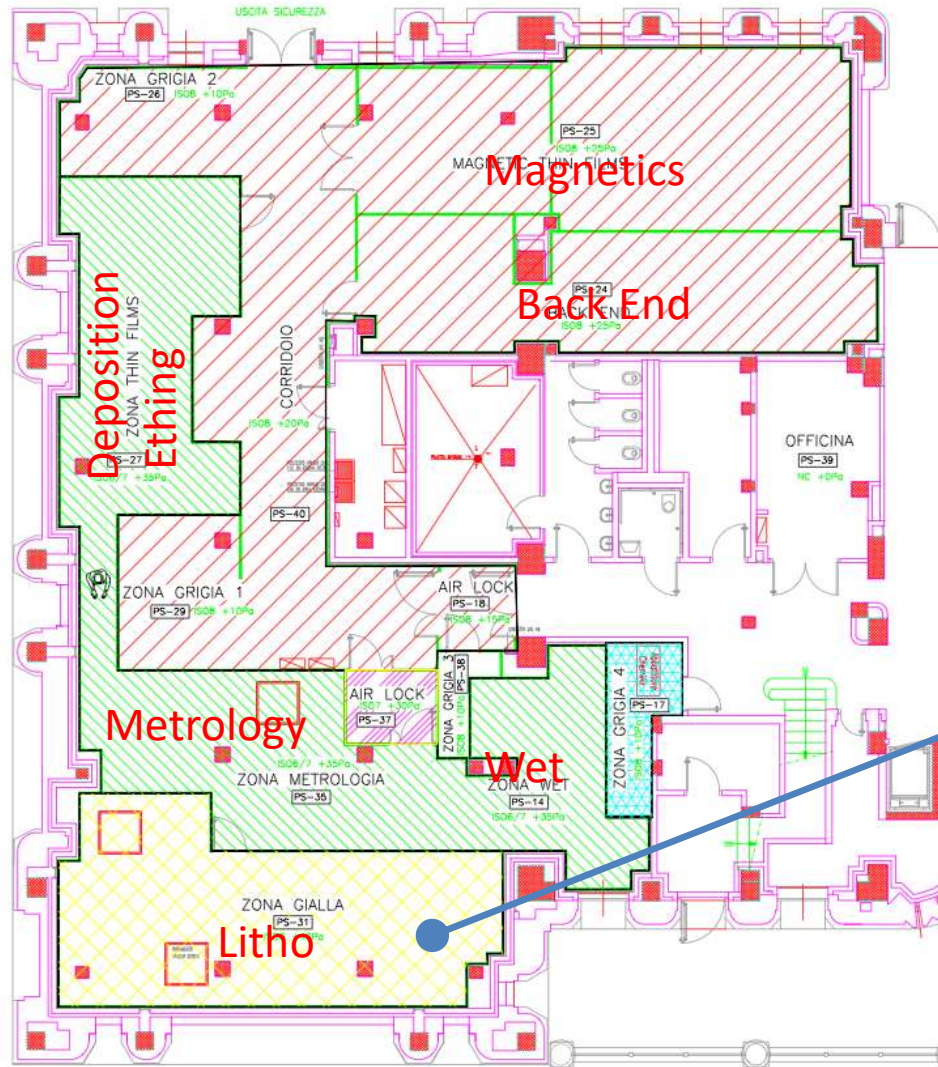
Timeline 2016



July 3, 2015



Photolitho and EBL



Photolitho and EBL

Mask aligner

Laser writer

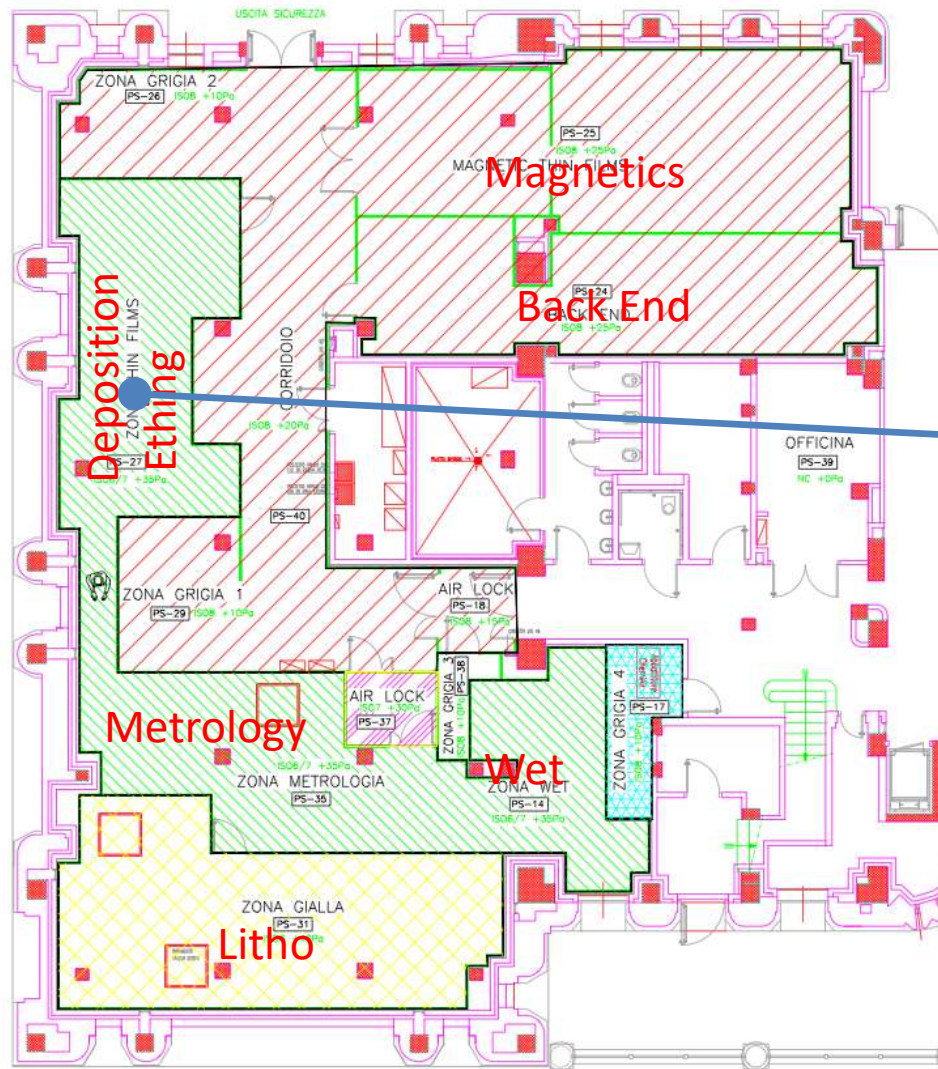
SEM - EBL writer

Spin coater

Ovens, hot plates

Benches for resist development

Deposition and etching

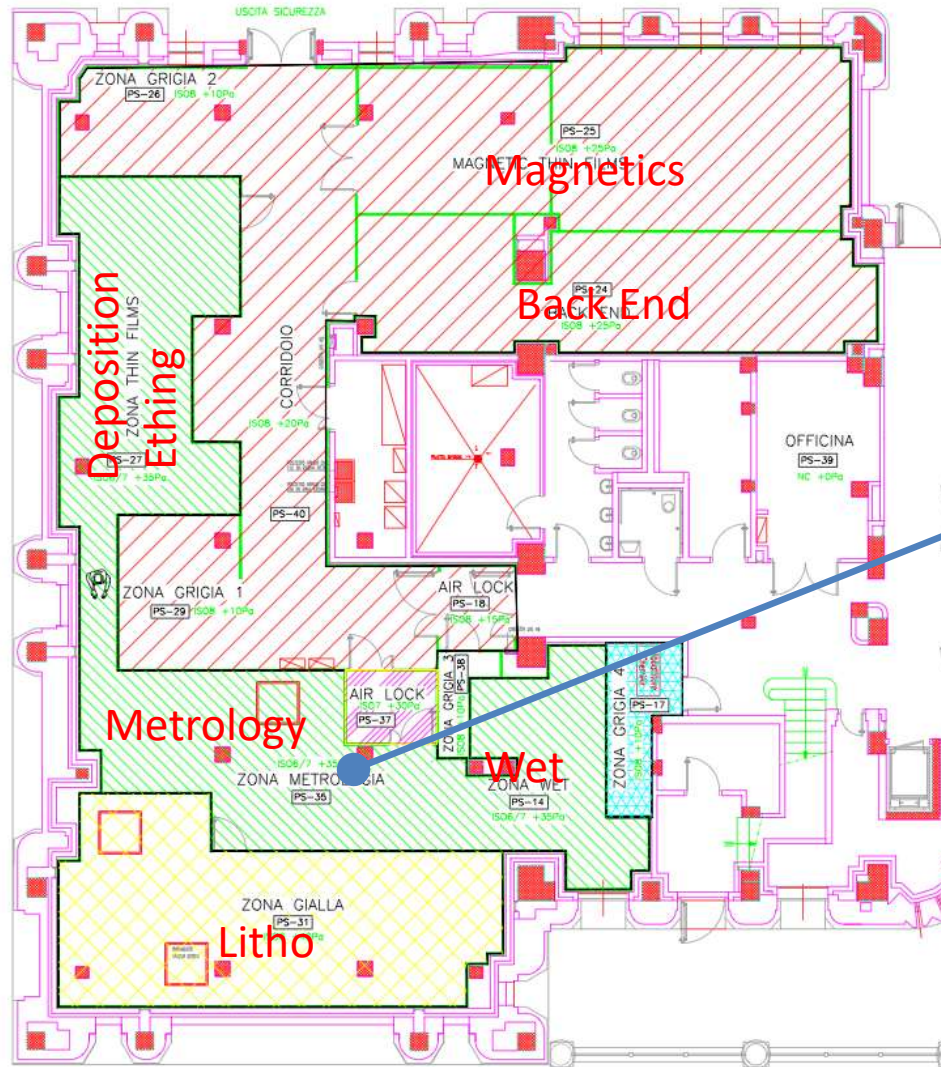


Thin films deposition
Magnetron Sputtering
(RF and DC)
E-beam evaporator
PECVD
Rinse & dryer

Dry etching
Ion Beam Etching
Reactive Ion Etching
Plasma cleaning

Wet process
Electroplating

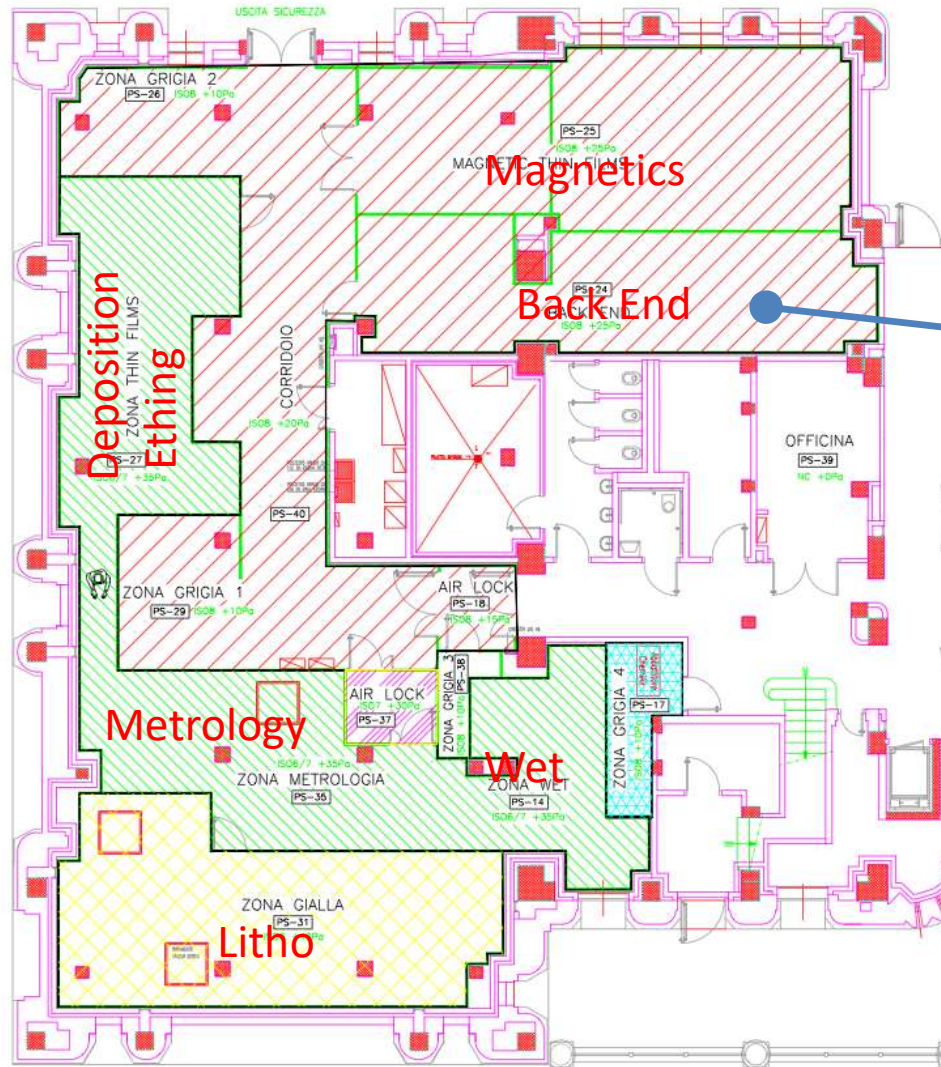
Wet processes and metrology



Wet processes
Chemical etching
(organics and inorganics)
Lift-off

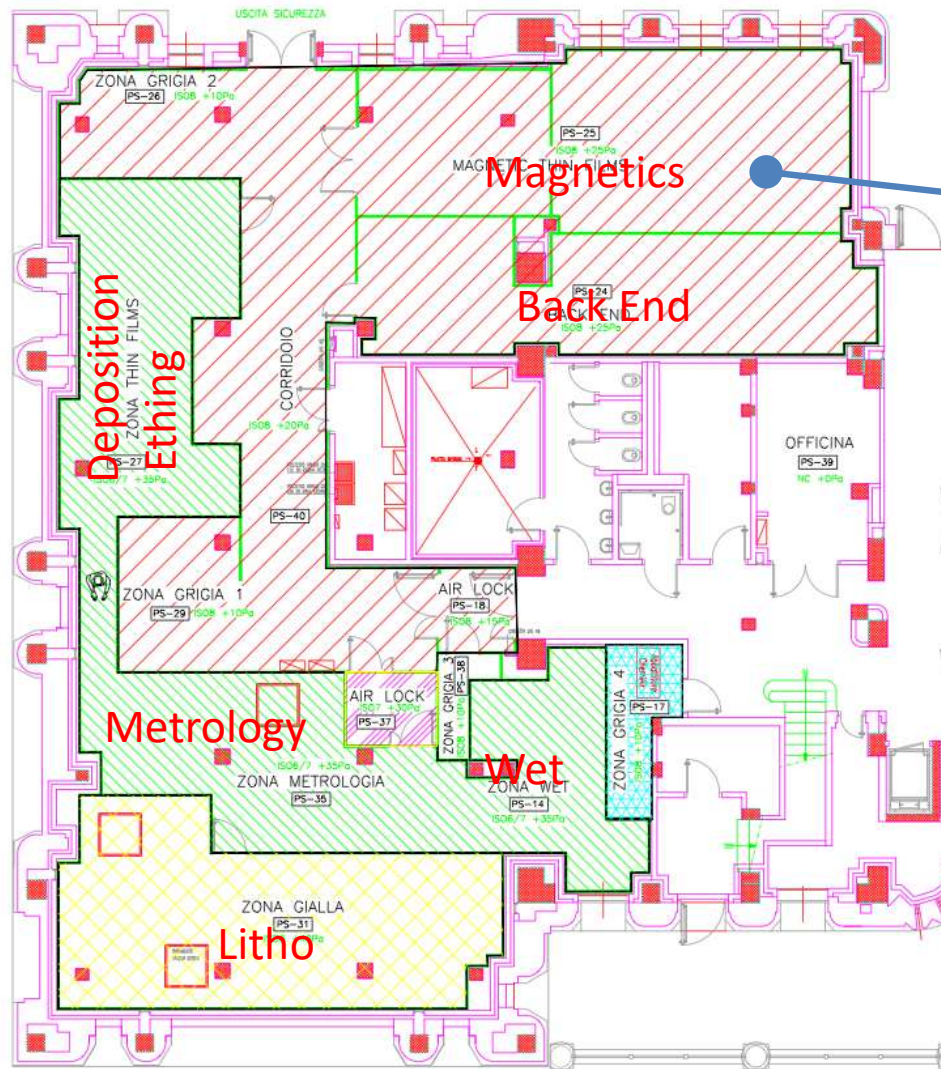
Metrology
Spectroscopical
ellipsometry
Profilometer
AFM
Metricon
Electrical resistivity

Annealing and back-end



- Annealing
- Furnaces (900°C)
- RTPA
- Back-end
- Dicing saw
- Wire bonding
- Lapping
- Wafer mounting
- PDMS
- Microfluidic facility

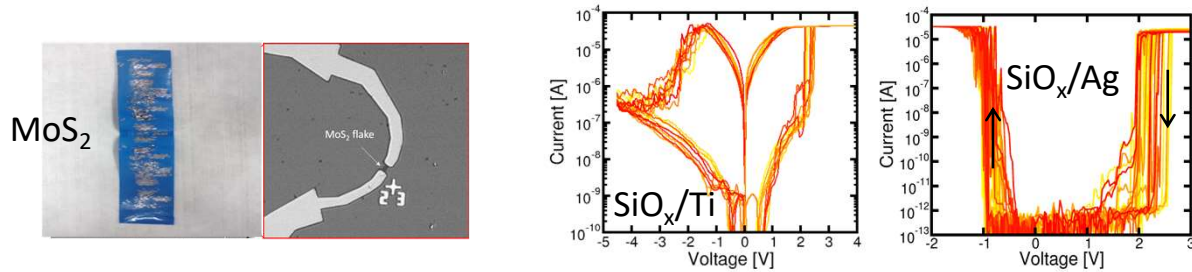
Magnetics



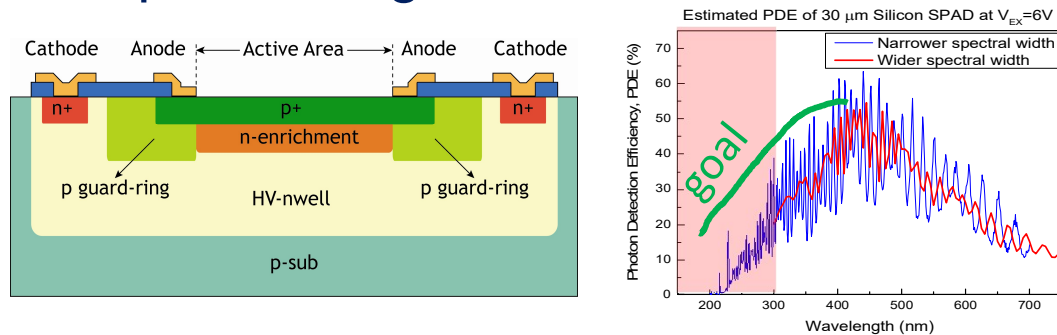
Magnetics
MBE cluster
Sputtering

Micro-nanoelectronics

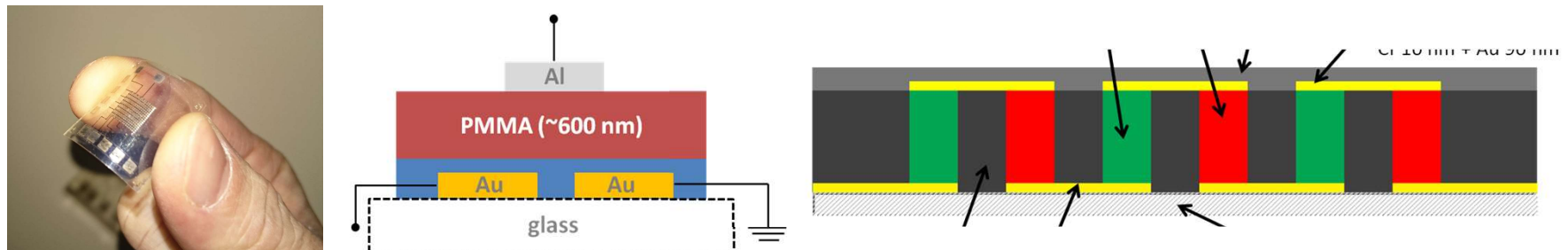
Development of ReRAMs, selectors, prototypes of 2D transistors



Post-processing of SPADs for enhanced IR detection efficiency

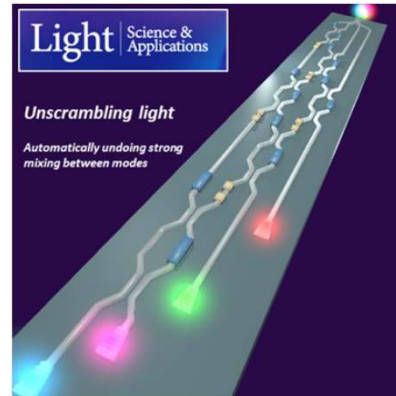


Micro contacts for OLED and OTEG

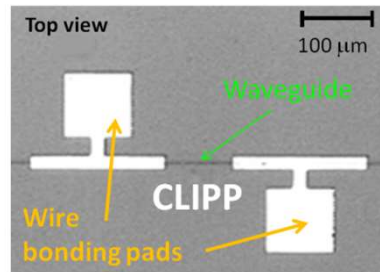
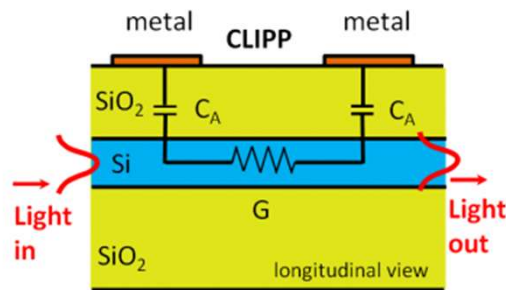


Photonics

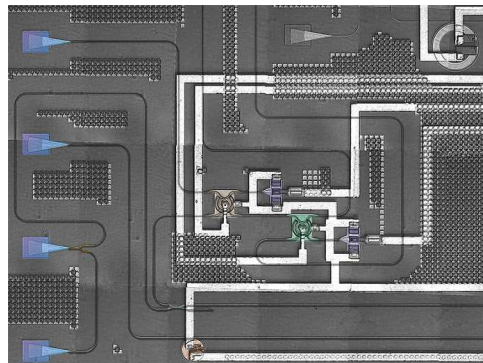
Photonic components



Photonic sensors



Photonic circuits for quantum photonics



Fabrication equipment

PE-CVD

RIE

Optical/Electronic Lithography

Laser writer

Characterization Equipment

Ellipsometry

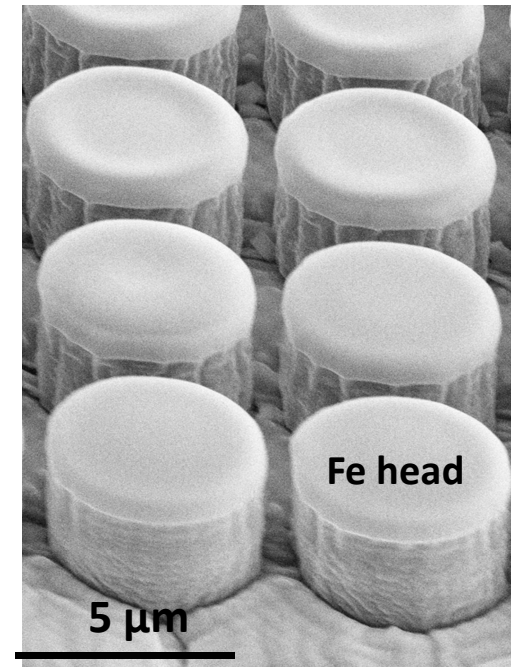
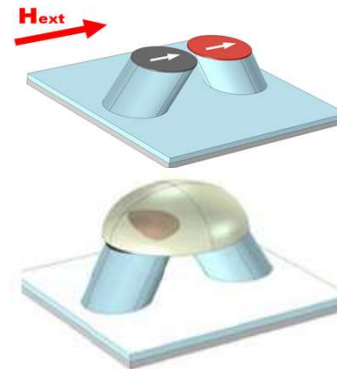
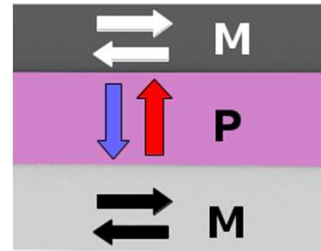
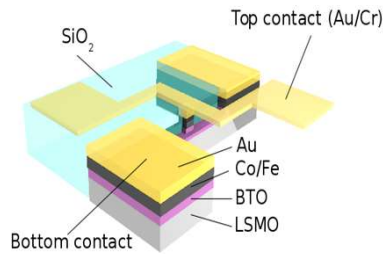
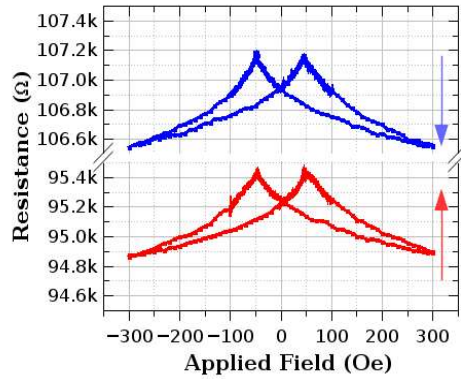
Metricon

Profilometer

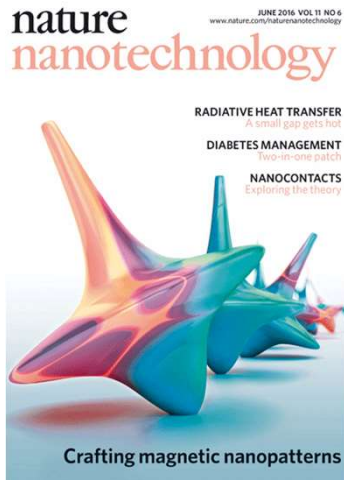
SEM

Nano-Magnetics

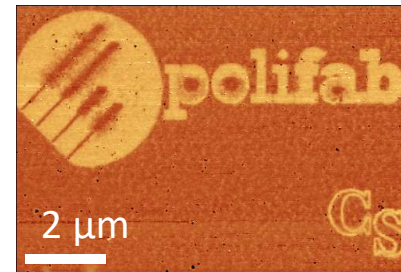
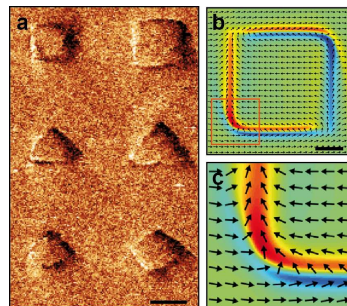
Multiferroic Tunneling junctions for information storage



Magnetically actuated devices

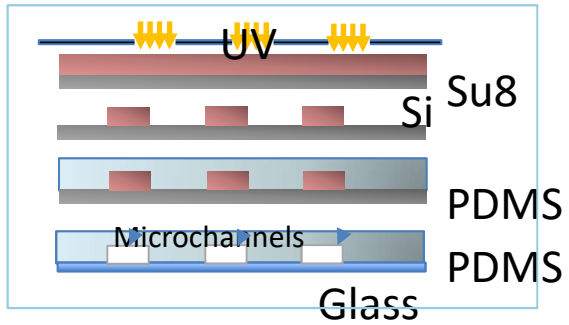


Nanopatterning techniques

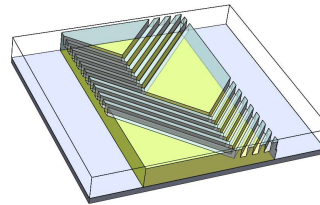


PDMS pillar

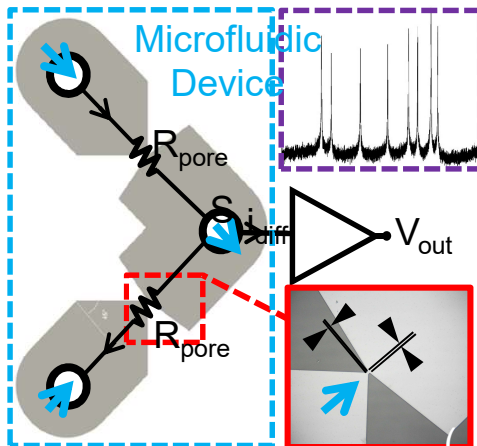
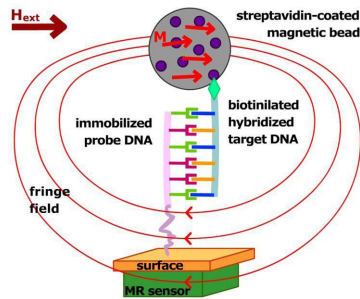
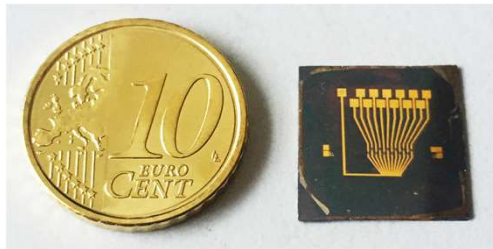
Microfluidics



Microfluidic devices for rare cell detection



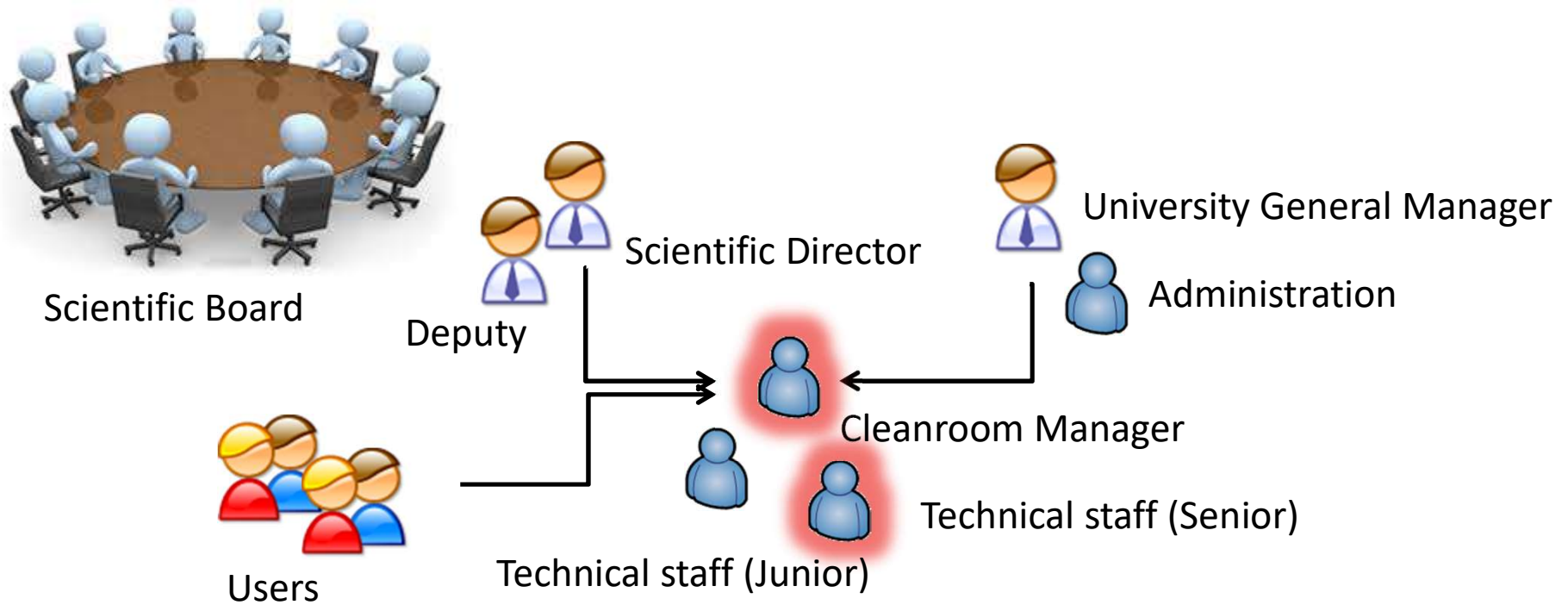
Magnetic biosensors



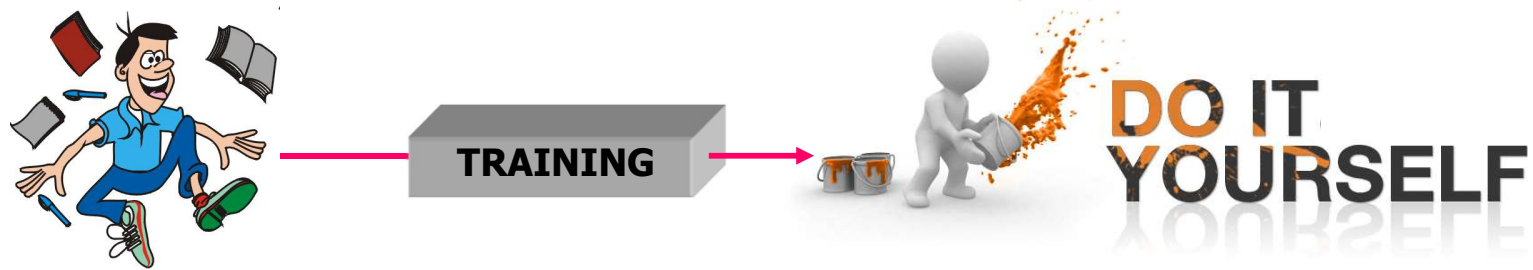
Pharmaceuticals

Counting antibody aggregates

Governance



1. «hands-on» - direct access to the cleanroom after safety qualification.



2. «service» - processing made by PoliFab personnel

